

HabEx Coronagraph Masks in Polarization Ray-tracing

M. Kupinski, PhD, Associate Research Professor

J. B. Breckinridge, PhD, Professor

J. Davis, PhD candidate

B. Daugherty, PhD candidate

R. Chipman, PhD, Professor

College of Optical Sciences, University of Arizona, Tucson.

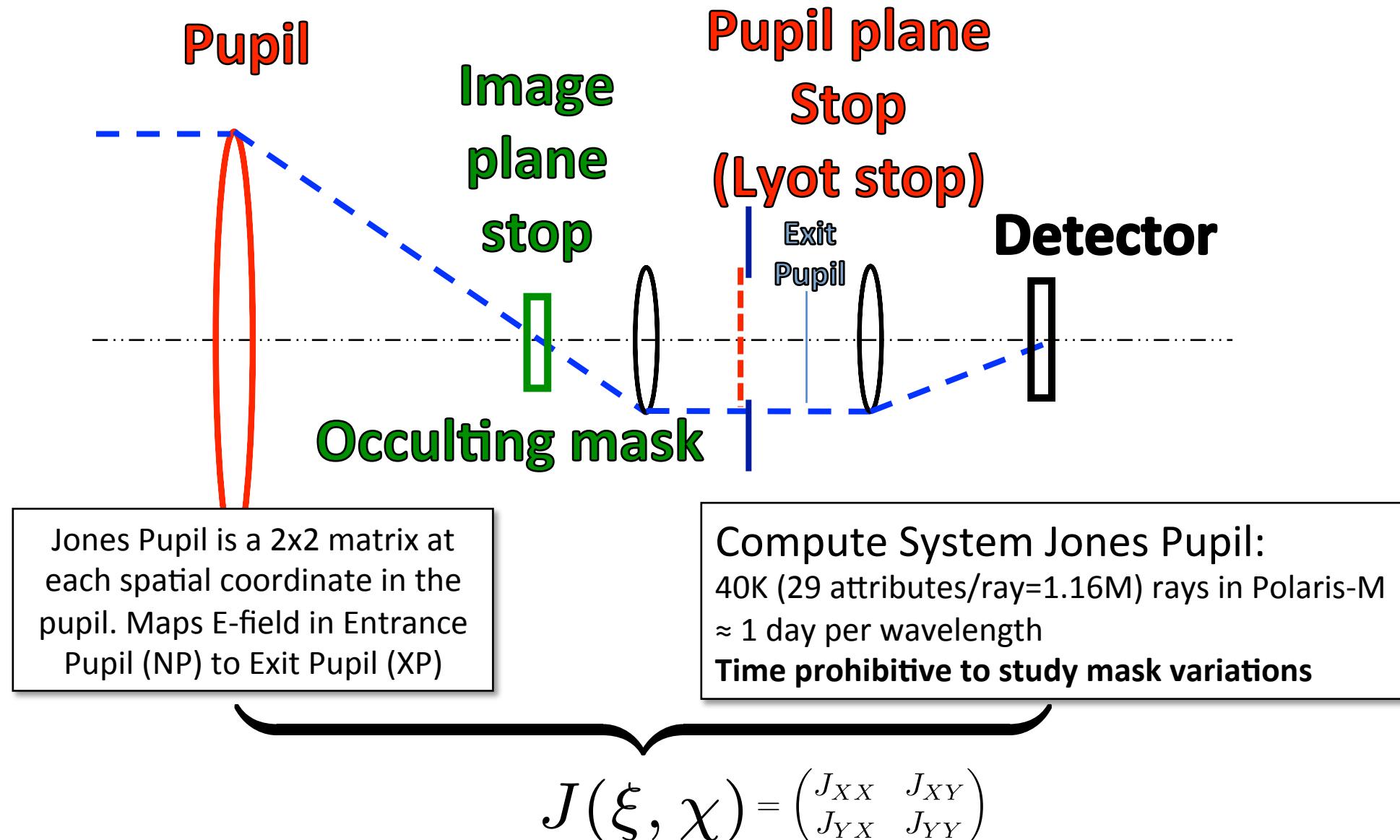
Presentation Outline

- Computational methods for using polarization ray tracing to study coronagraph designs with a Jones Pupil decomposition
- Measurements/modeling of form birefringence on primary mirror
 - Degrades contrast
- Future work:
 - Mitigation strategies in mask design
 - Sensitivity to mask fabrication errors

Assumptions in these Simulation Studies

- No deformable mirror optimization or EFC in HabEx prescription
- Measurements/modeling of form birefringence on primary mirror
 - Demonstration of capability to quantify degradation in contrast
 - Novel method for measuring form birefringence on a large optic
 - Test optic we measured is NOT HabEx mirror and given differences in coating technology our measurements are a worse case scenario (maybe 10x better is possible?)

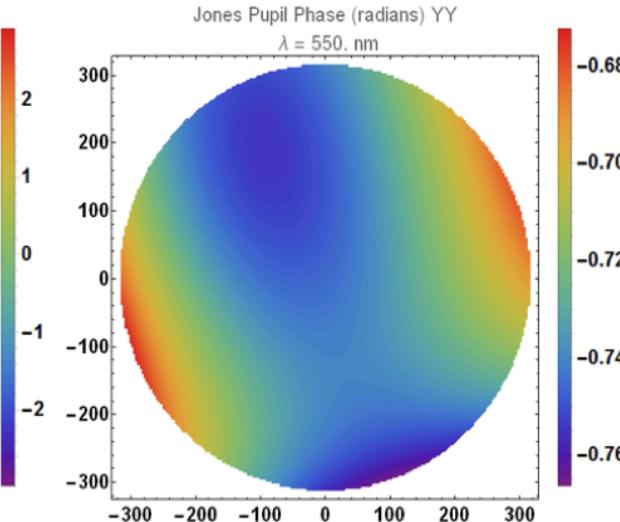
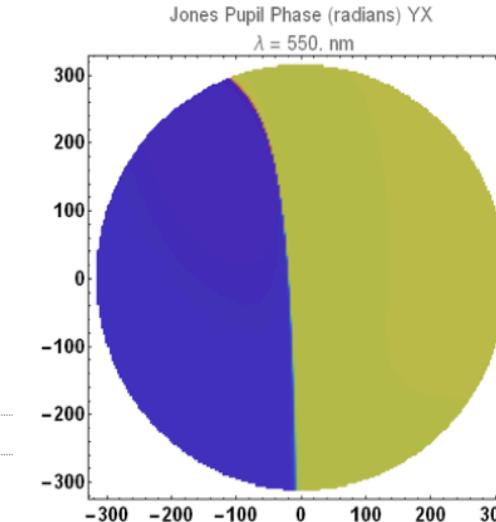
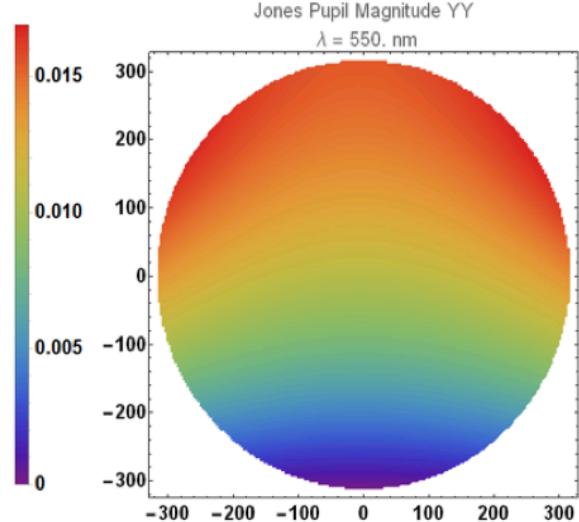
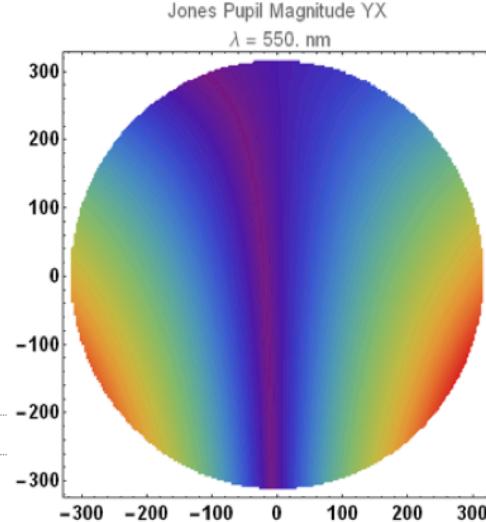
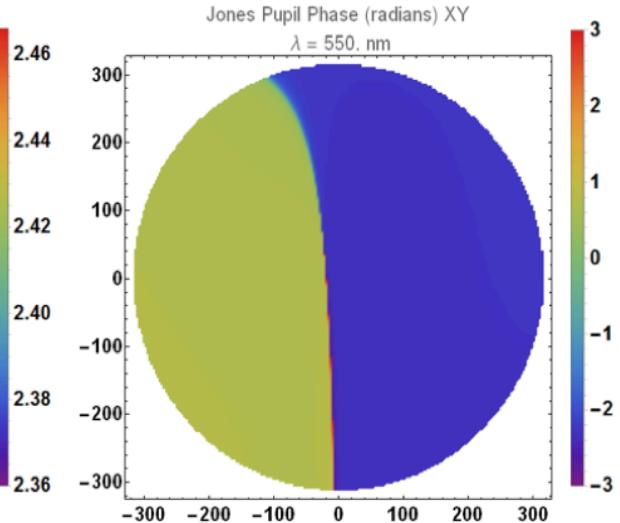
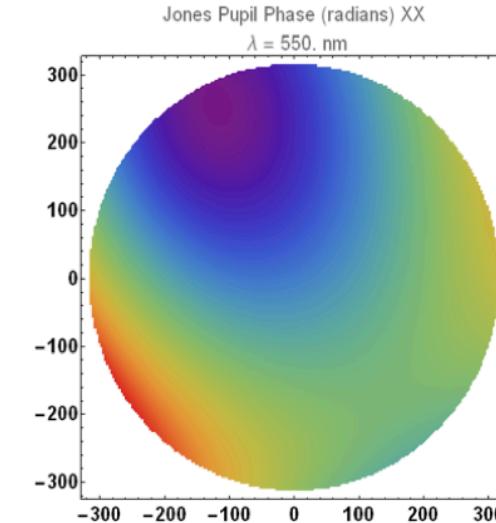
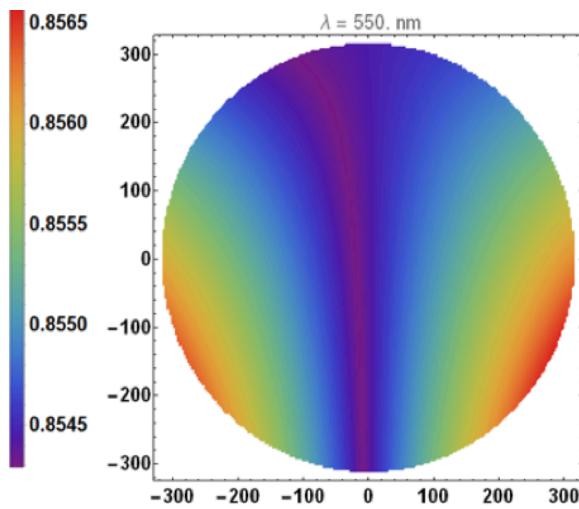
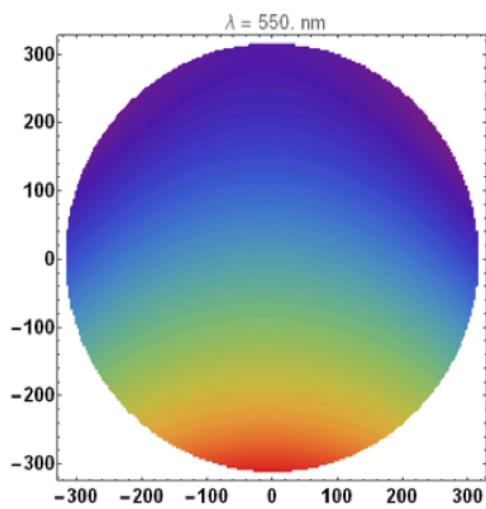
Computing the HabEx Jones Pupil using Polaris-M



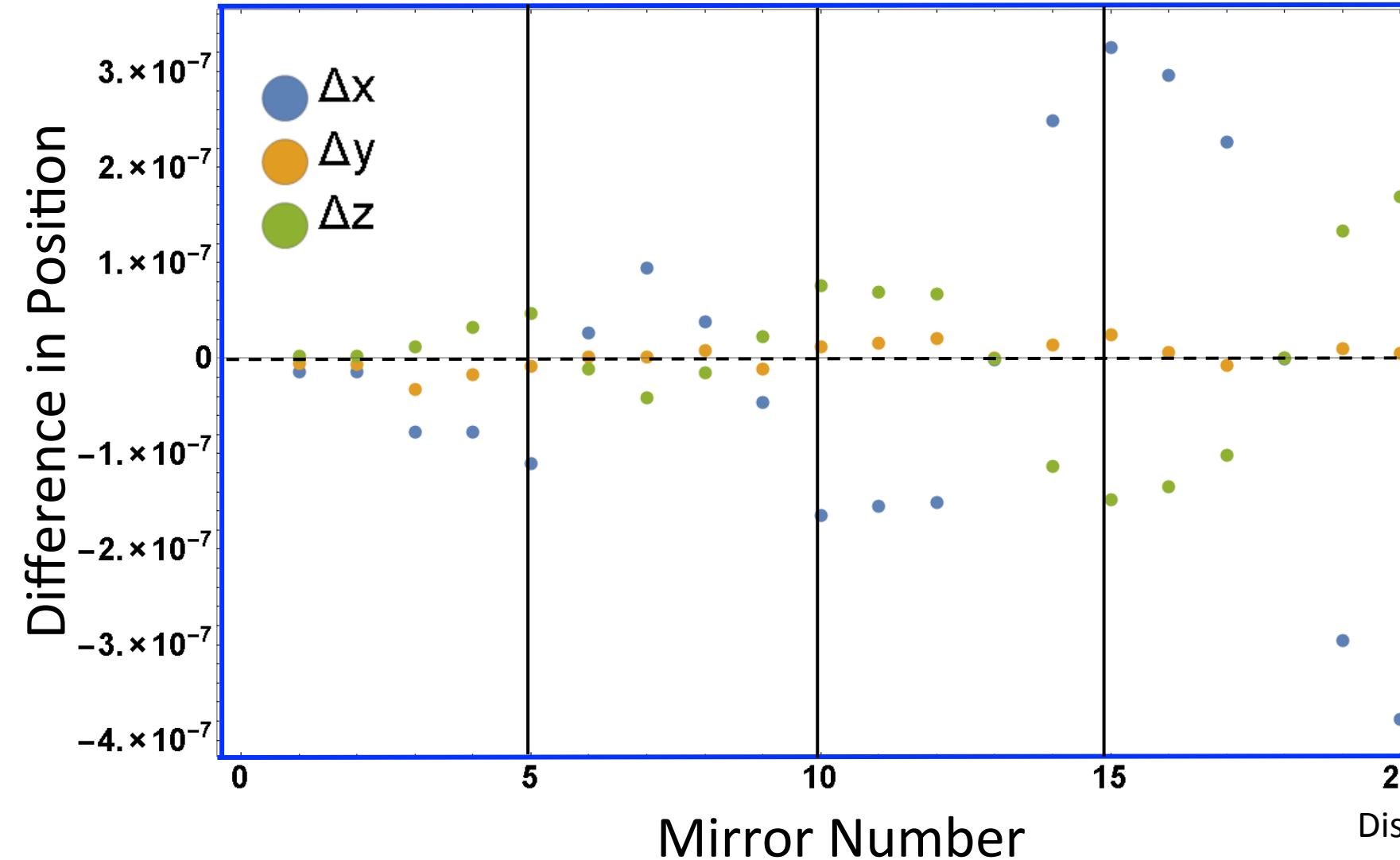
HabEx Jones Pupil from Polaris-M: detector plane @ 550 nm(no mask)

Amplitude

Phase [radians]



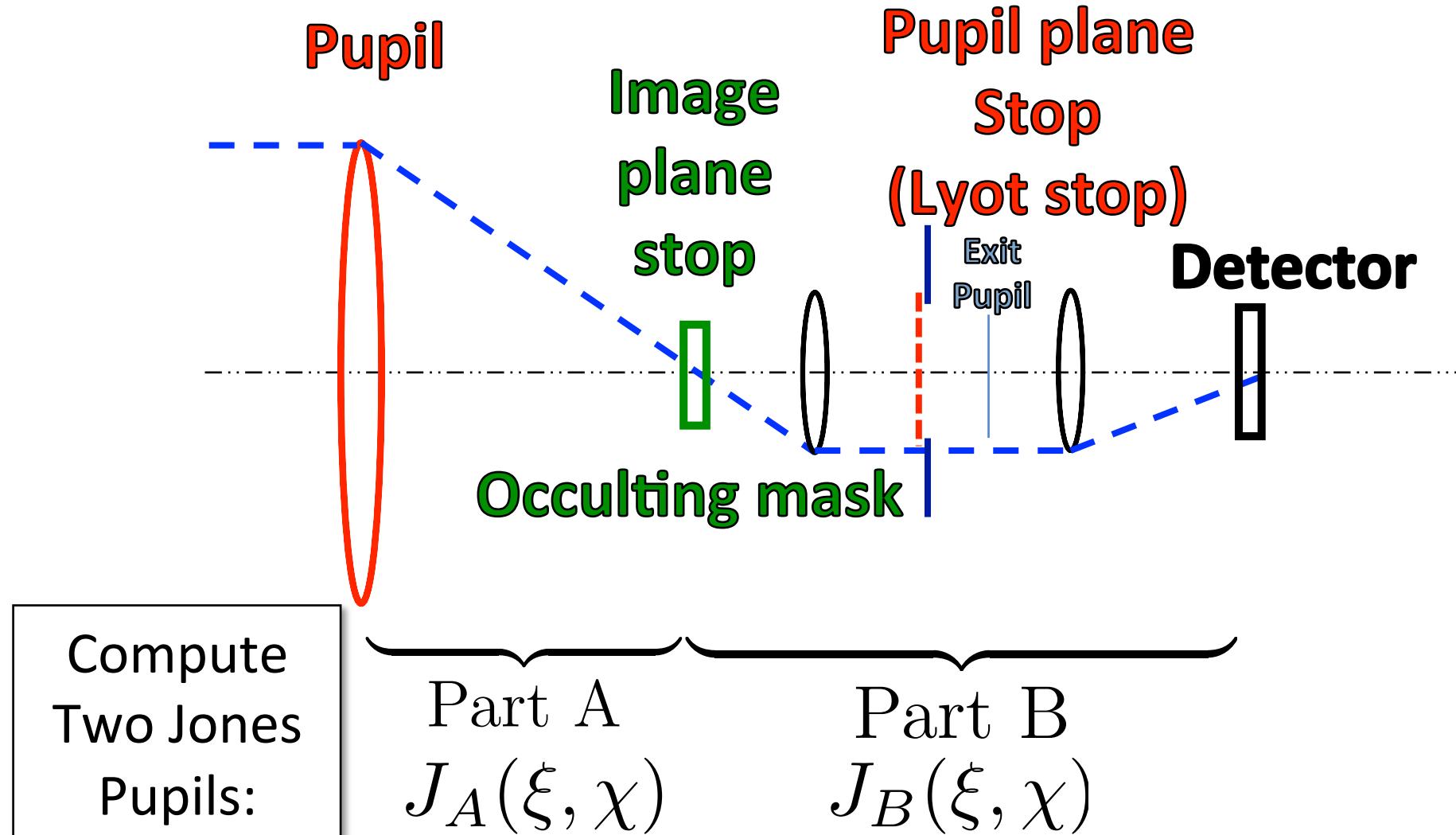
Code-V & Polaris-M Validation



k-vector residual
 $< 3 \times 10^{-7}$ mm
on mirror surfaces
for WFIRST-CGI

Computing the HabEx Jones Pupil with Mask

Pupil Decomposition Concept to Eliminate Redundancy



Implementing the HabEx Mask: *Pupil Decomposition Algebra*

No Mask:

$$J(\xi, \chi) = J_B(\xi, \chi) J_A(\xi, \chi)$$

2x2 matrix-multiply

Insert Mask (**without redoing fore-optics & instrument ray trace!**):

$$J(\xi, \chi) = J_B(\xi, \chi) \mathcal{F}^{-1} \{ M \odot \mathcal{F} \{ J_A(\xi, \chi) \} \}$$

M : complex transmittance of the mask

Element-by-element multiply

Analyze the behavior of the Jones Pupil, PSF, system contrast for various mask designs:

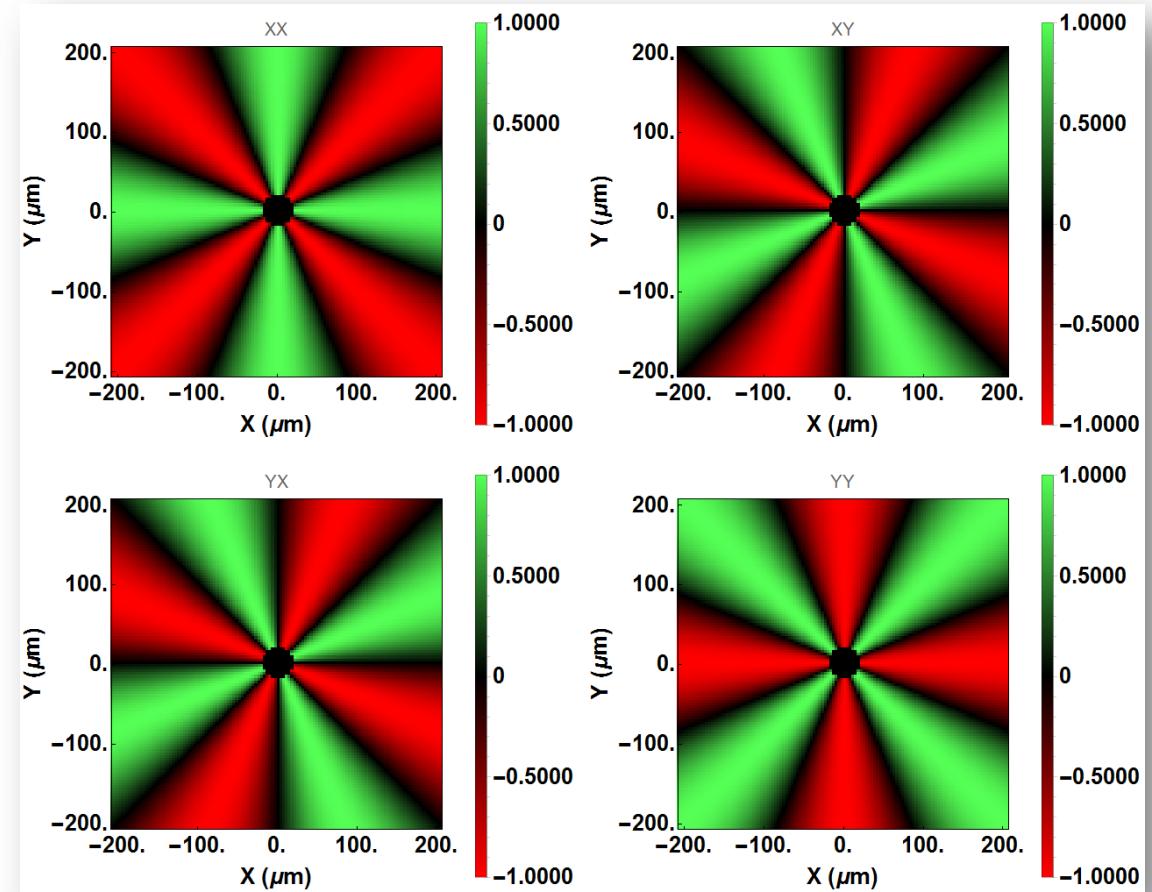
$$J(\xi, \chi; \mathbf{a}) = J_B(\xi, \chi) \mathcal{F}^{-1} \{ M(\mathbf{a}) \odot \mathcal{F} \{ J_A(\xi, \chi) \} \}$$

\mathbf{a} : mask attributes (e.g. size occulter, phase errors, fabrication tolerances)

Vector Vortex (VV) Transmittance

$$\begin{pmatrix} \cos(m \tan^{-1}(\frac{y}{x})) & \sin(m \tan^{-1}(\frac{y}{x})) \\ \sin(m \tan^{-1}(\frac{y}{x})) & -\cos(m \tan^{-1}(\frac{y}{x})) \end{pmatrix}$$

- Vector Vortex (charge, m=4)
- 40 micron diameter obscuration
- Future work:
 - Fabrication tolerances for liquid crystal VV



Presentation Outline

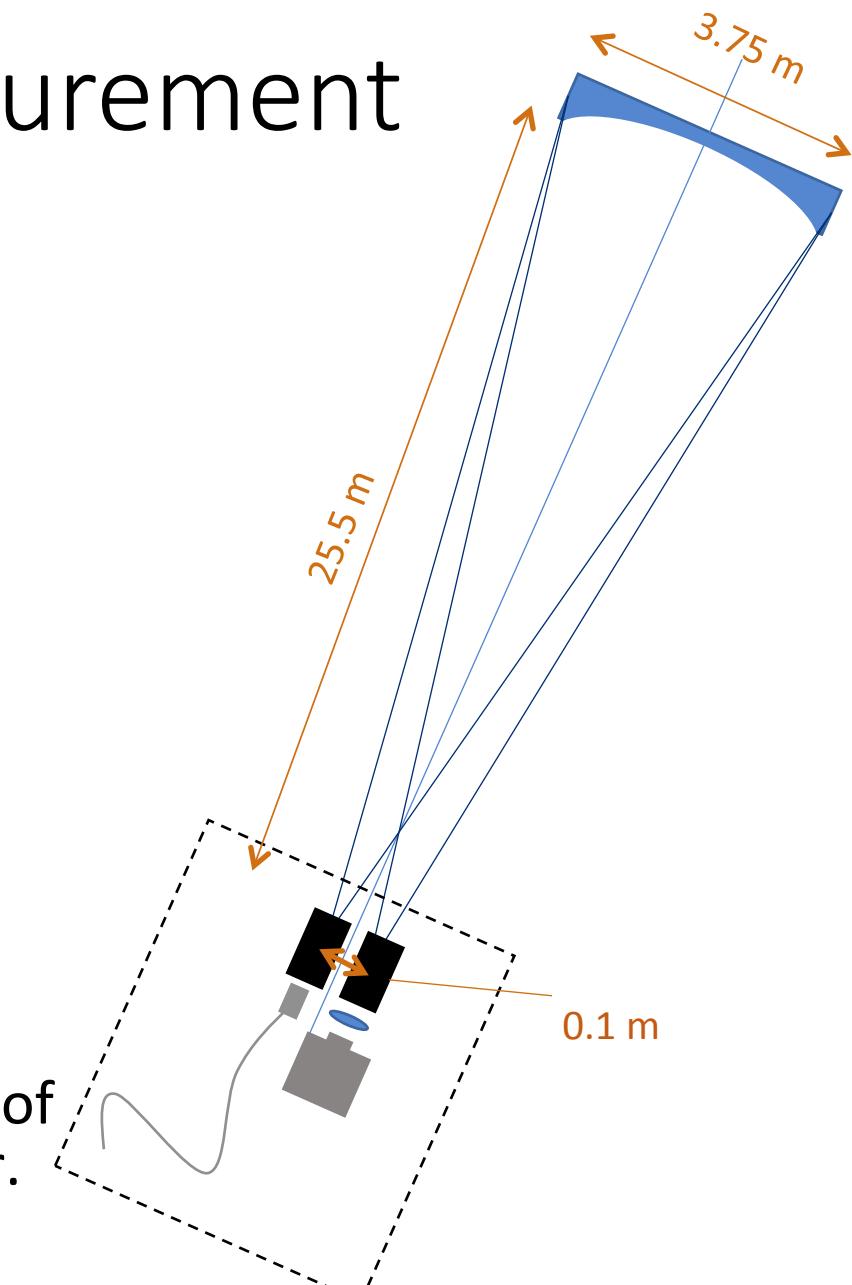
- Computational methods for using polarization ray tracing to study coronagraph designs with Jones Pupil decomposition
- **Measurements/modeling of form birefringence on primary mirror**
 - Degrades contrast
- Future work:
 - Mitigation strategies in mask design
 - Sensitivity to mask fabrication errors

Primary mirror form birefringence effects

- Took advantage of a unique opportunity to measure spatial changes in polarization reflectivity across a large (3.75-m) astronomical mirror
 - Al coated in a vacuum chamber at Kitt Peak
 - Bare Al natural oxide layer about 4nm
- Developed a precision instrument and software to measure birefringence and diattenuation across a 3.75-meter mirror
- Placed the measured results into our HabEx model & modeled the effect on the noise-equivalent contrast.

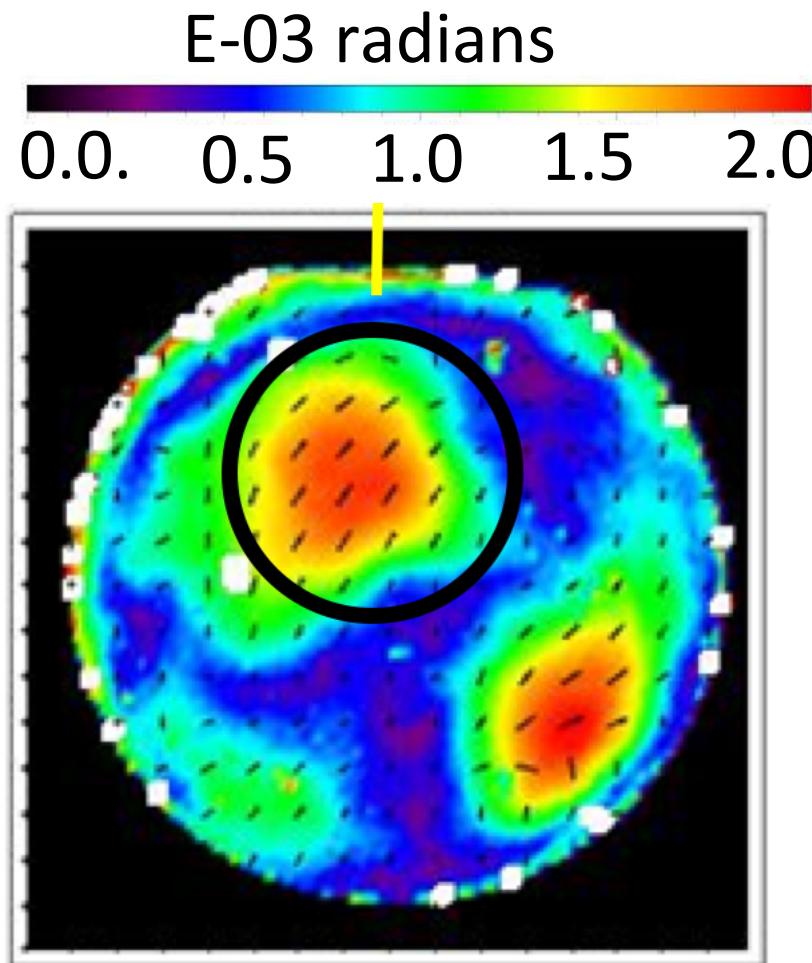
Form Birefringence Measurement

- Measurement concept
 - Identify polarization properties intrinsic to coating
 - Incident angles near 0° achieved by placing point source adjacent to center of curvature of mirror
 - With this geometry Fresnel equations predict
 - retardance $< 10^{-5}$
 - diattenuation $< 10^{-6}$
- System description
 - Source: Fiber coupled monochromator
 - Polarimetry: Two crossed Glan-Thompson polarizers mounted on motorized rotation stages
 - Detector: Scientific grade 16-bit camera
 - Mounting: 3-axis translation to align system with center of curvature. 2-tilt axis to aim source and camera at mirror.
 - Rotation about center axis to provide different system orientations

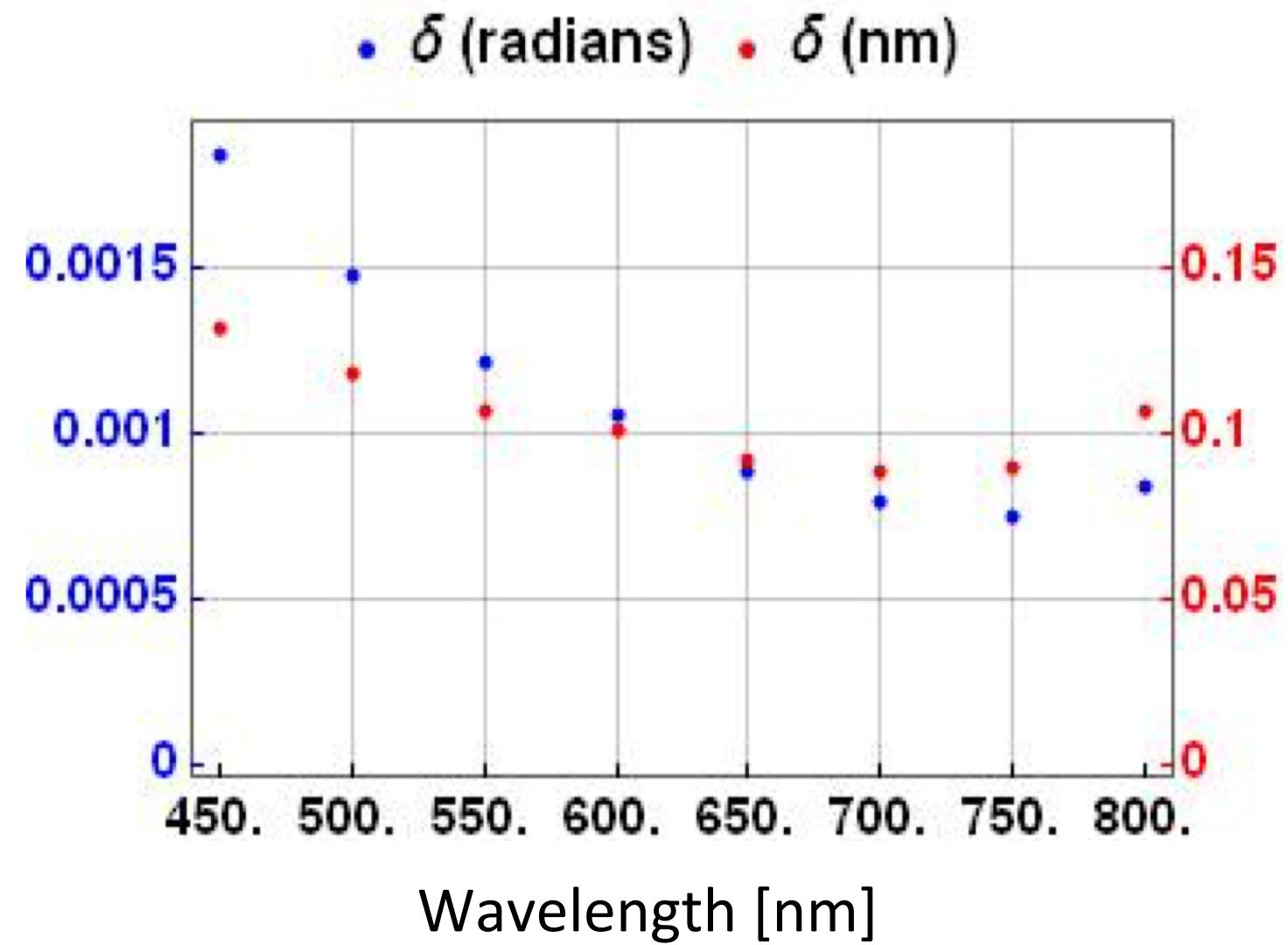


Dissertation work of Brian Daugherty

Form Birefringence Measurement



Dissertation work of Brian Daugherty



Noise Equivalent Contrast

Definition

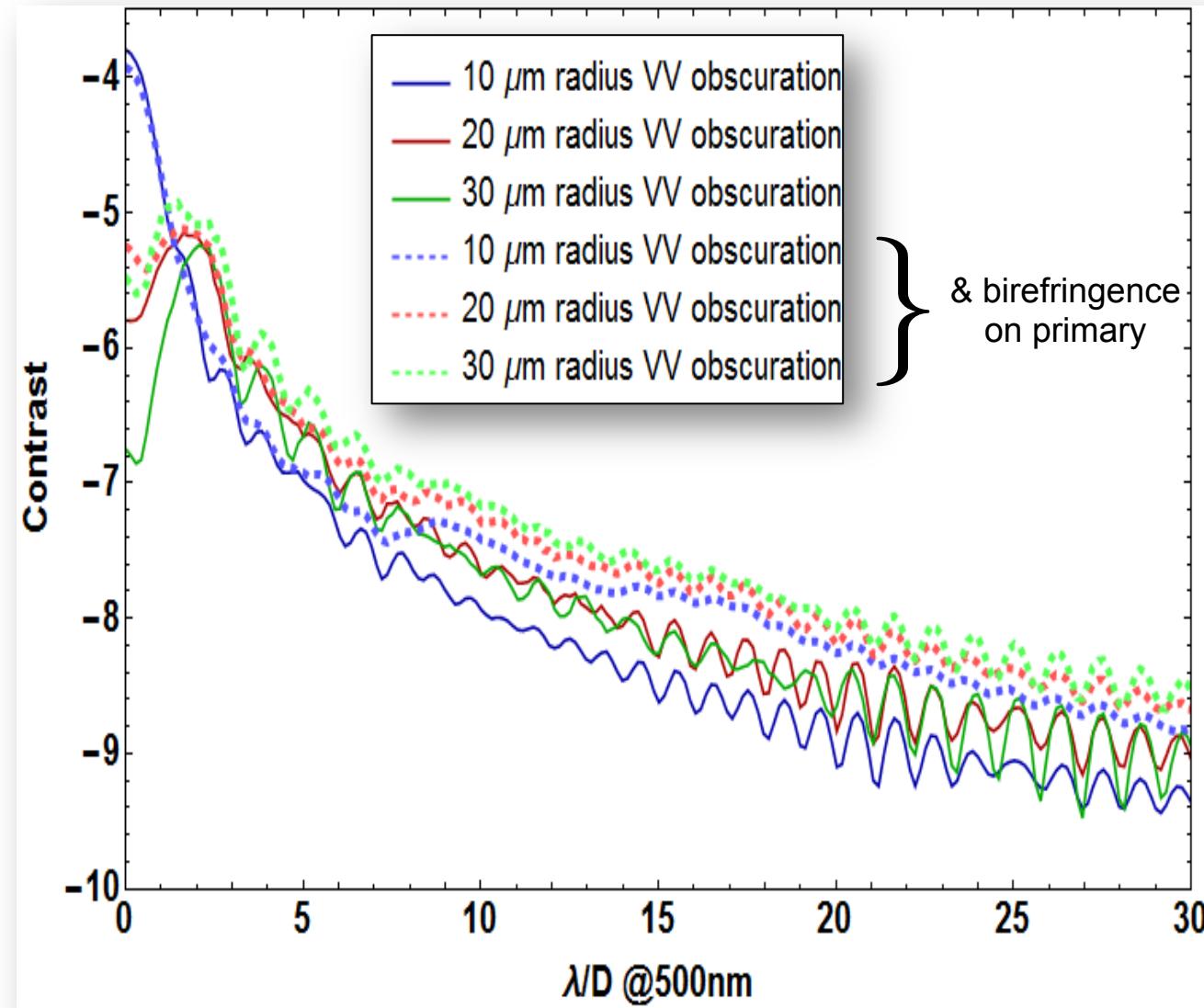
$$C_{\Delta(500)}^P(\mathbf{r}) = \log_{10} \left[\frac{1}{2} \left(\frac{\sum_{\lambda=450}^{\lambda=550} \langle I_{XX}(\mathbf{r}; \lambda) + I_{YY}(\mathbf{r}; \lambda) \rangle_{\mathbf{r}}}{\sum_{\lambda=450}^{\lambda=550} I_{XX}^{NoMask}(0; \lambda) + I_{YY}^{NoMask}(0; \lambda)} \right) \right]$$

where

$$PSF(x, y) = \begin{pmatrix} I_{XX}(x, y) & I_{XY}(x, y) \\ I_{YX}(x, y) & I_{YY}(x, y) \end{pmatrix}$$

- Sum the on-diagonal polarimetric elements
- Numerator is poly-chromatic PSF with occulting mask
- Denominator unmasked PSF at origin

HabEx 1709; Contrast [450, 475, 503, 525, 550 nm] with and without birefringence on primary mirror



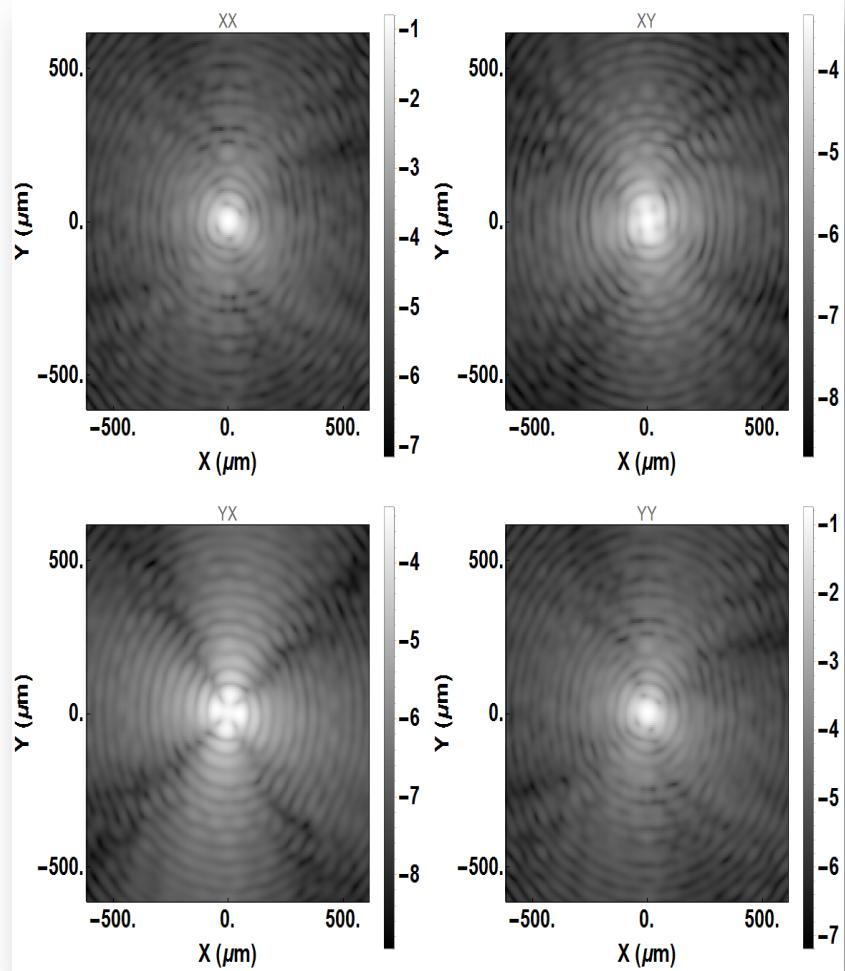
Approximately 5x
degradation in contrast
when including form
birefringence on primary
mirror

Dissertation work of Jeff Davis

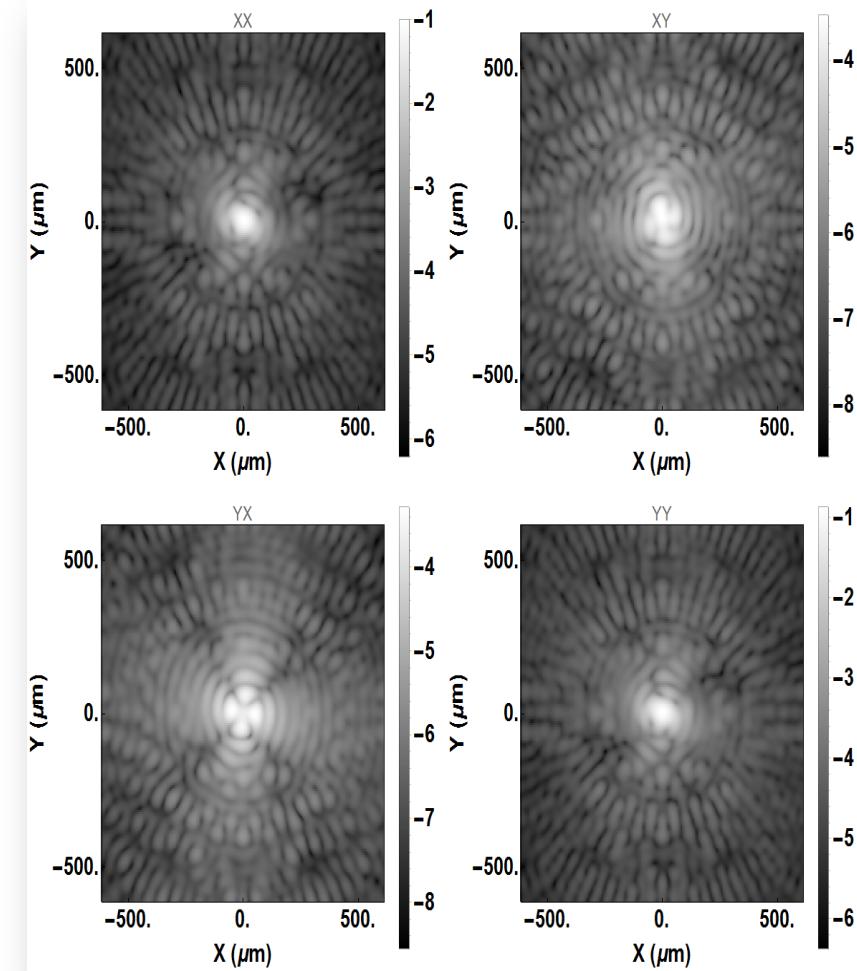
HabEx 1709; Log10 PSF [450=>550 nm]

VV4 (obscuration radius 10 microns)

No Birefringence on primary

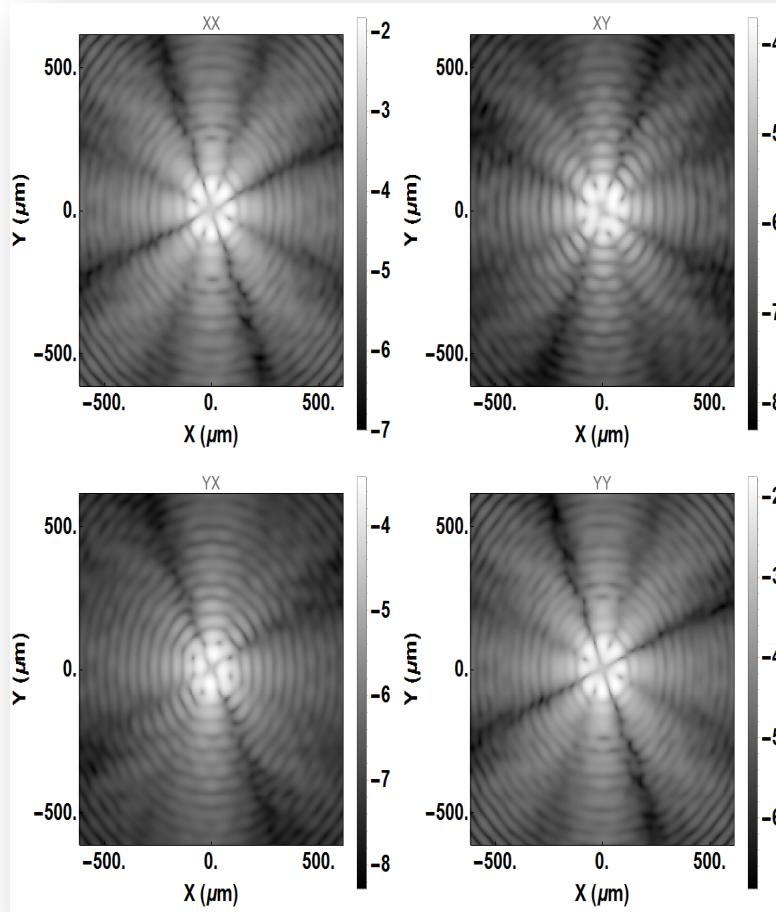


Birefringence on primary

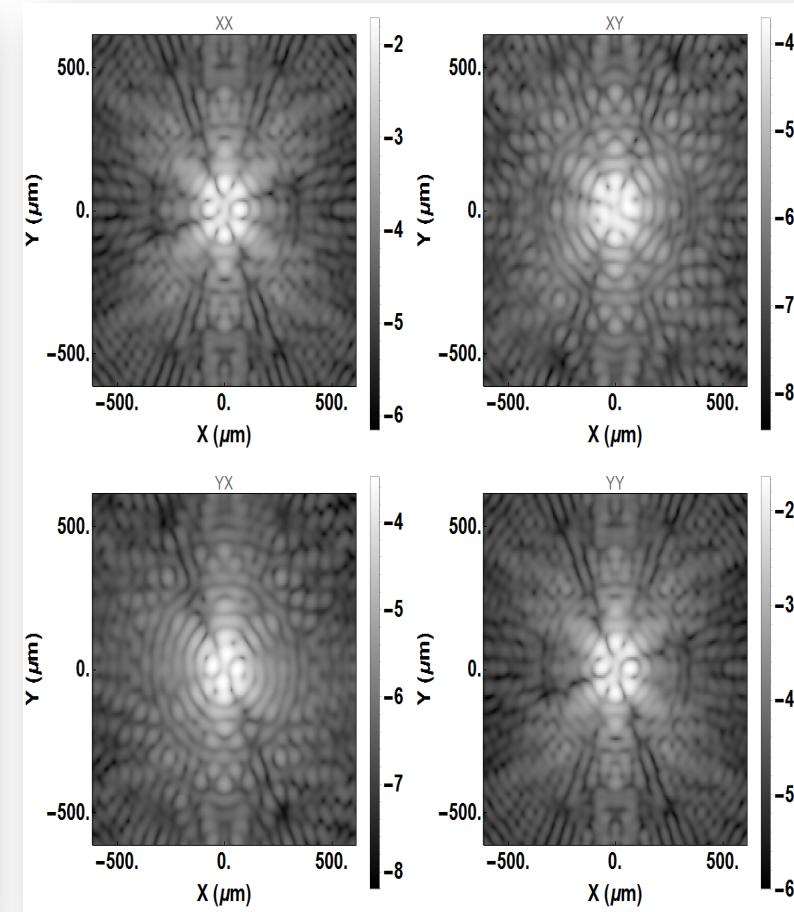


HabEx 1709; Log10 PSF [450=>550 nm] VV4 (obscuration radius 20 microns)

No Birefringence on primary

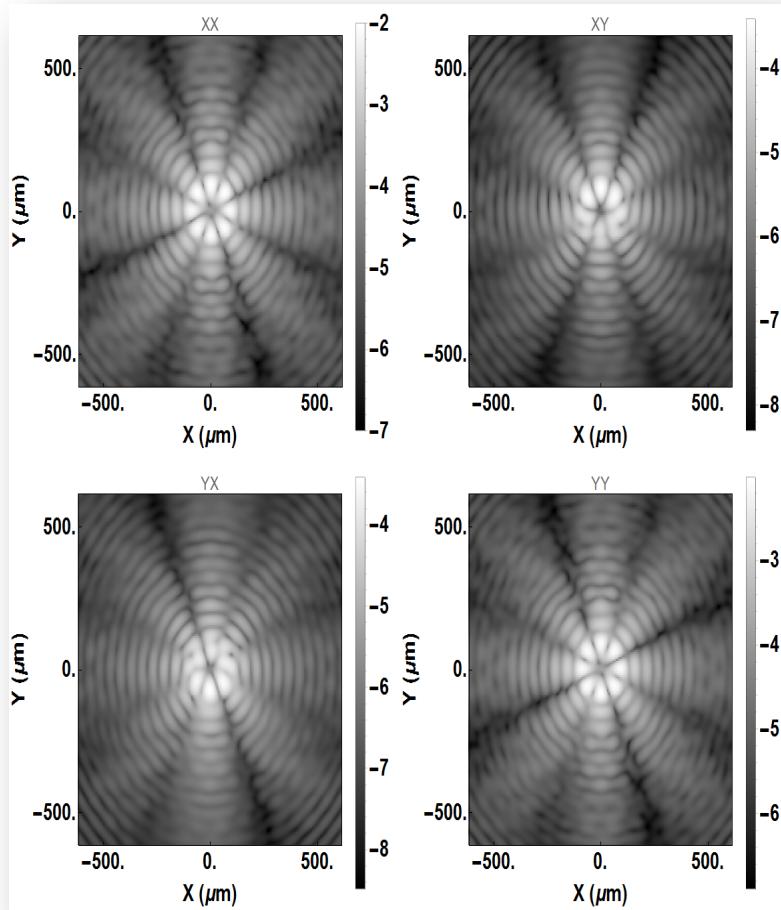


Birefringence on primary

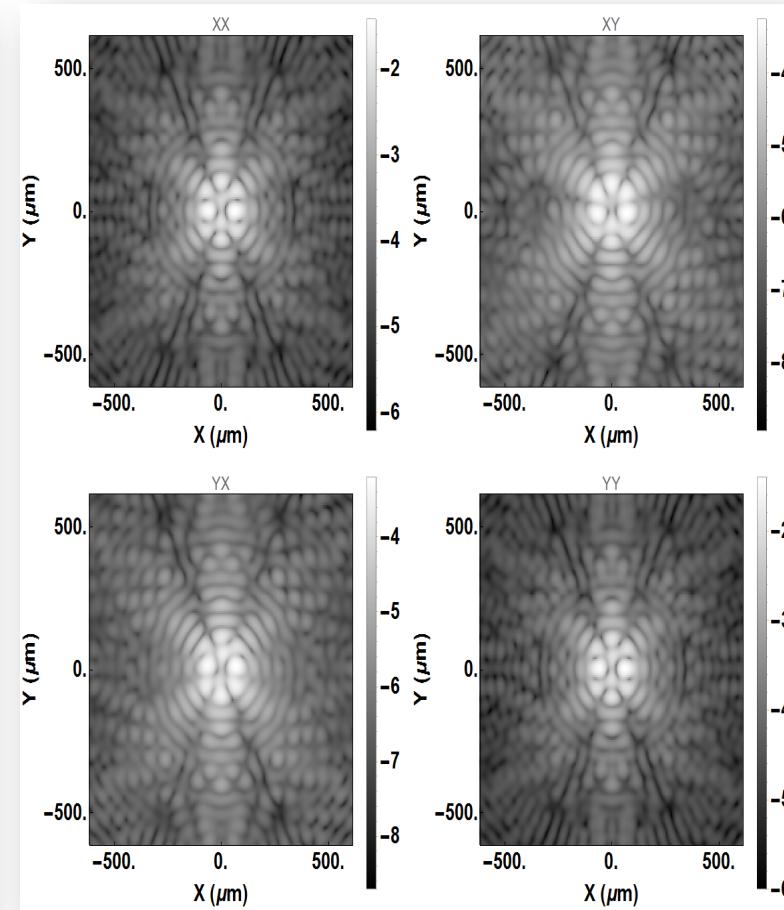


HabEx 1709; Log10 PSF [450=>550 nm] VV4 (obscuration radius 30 microns)

No Birefringence on primary



Birefringence on primary



Conclusions

- Polarization ray tracing can be made computational feasible for studying mask designs and polarization properties of large optics with Jones Pupil decomposition
- Polarization and form birefringence degrades contrast
- Future work:
 - Are mitigation strategies in mask design possible?
 - Sensitivity to mask fabrication errors
 - Treat polarization properties of surfaces as random processed

Future Work

Optimize Linear System between E-field at entrance pupil (NP) and exit pupils (XP):

$$E_{XP} = J(\xi, \chi; \mathbf{a}) E_{NP}$$

- Create Scene Models (spectra-polarimetric) for E_{NP} under 2 hypotheses, eg: exoplanet present, exoplanet habitable, atmospheric dust/disk types
- Optimize mask attributes for discriminating these 2 hypotheses from E_{XP}
- Expertise in this type of optimization problem for scientific imaging:
 - Use Kullback-Leibler divergence between $\text{pr}(E_{XP}|1)$ and $\text{pr}(E_{XP}|2)$ as merit function
 - Closed-form gradient wrt mask attributes for normal $\text{pr}(E_{XP}|1)$ and $\text{pr}(E_{XP}|2)$